

Claims

1. Substrate treatment equipment having,
a substrate treatment chamber,
a substrate holder that can be inserted into the substrate treatment chamber and holds substrates in a multistage manner in a substantially vertical direction,
a substrate transfer unit for transferring the substrates into the substrate holder,
and a sensing device for sensing a holding condition of the substrates held in the substrate holder; characterized by including,
a control device that, in transfer of the substrates, senses the holding condition of the substrates using the sensing device, and controls the substrate transfer unit such that substrates other than a substrate which was determined to be in an abnormal substrate holding condition are transferred by the substrate transfer unit.
2. The substrate treatment equipment according to claim 1, characterized in that the control device controls the substrate transfer unit such that substrates other than the substrate determined to be abnormal and at least one of substrates held on and under the substrate determined to be abnormal are transferred by the substrate transfer unit.
3. A manufacturing method of a substrate, characterized by having,

a step of inserting a substrate holder on which substrates are held in a multistage manner in a substantially vertical direction into a substrate treatment chamber,

a step of performing heat treatment to the substrates in the substrate treatment chamber,

a step of sensing a holding condition of the substrates held in the substrate holder,

and a step of transferring substrates other than a substrate that was determined to be in an abnormal substrate holding condition by a substrate transfer unit.

4. The manufacturing method of the substrate according to claim 3, characterized in that the substrates are transferred in such a manner that substrates are carried for each of several predetermined number of substrates, and when all the predetermined number of substrates to be carried are determined to be in a normal substrate holding condition, all the predetermined number of substrates are carried together, and when at least one of the substrates is determined to be in an abnormal substrate holding condition, substrates other than the substrate that was determined to be abnormal in the predetermined number of substrates are carried one at a time.